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P/4178-10

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of
Yusuke MURAOKA et al.
Serial No.: 10/700,020
Filed: November 3, 2003

New York, New York
Date: May 27, 2004
Group Art Unit: --
Examiner: --

For: SUBSTRATE PROCESSING METHOD, SUBSTRATE PROCESSING APPARATUS
AND SUBSTRATE PROCESSING SYSTEM

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Further to the Submission dated January 23, 2004, attached hereto please find a corrected Form PTO-1449. The Examiner is requested to sign and return this form, instead of the form that was filed January 23, 2004.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents P.O. Box 1450, Alexandria, VA 22313-1450, on May 27, 2004

James A. Finder

Name of applicant, assignee or
Registered Representative

Signature

May 27, 2004

Date of Signature

Respectfully submitted,

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APPLICANT'S ART CITATION
(Use several sheets if necessary)

Application 10/700,020

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Applicant
Yusuke MURAOKA et al.

Filing Date
November 3, 2003

Group Art Unit ___

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	Filing Date If Appropriate
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	US-6,358,673	03-2002	Namatsu	430	311	
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						Yes	No
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	8-250464	09-1996	Japan				x
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		A Concise Explanation sheet

Examiner

Date Considered

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.